

Cross-cutting recombination metrology for expediting V_{OC} engineering

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PHOTOVOLTAICS RESEARCH AND DEVELOPMENT (PVRD1)

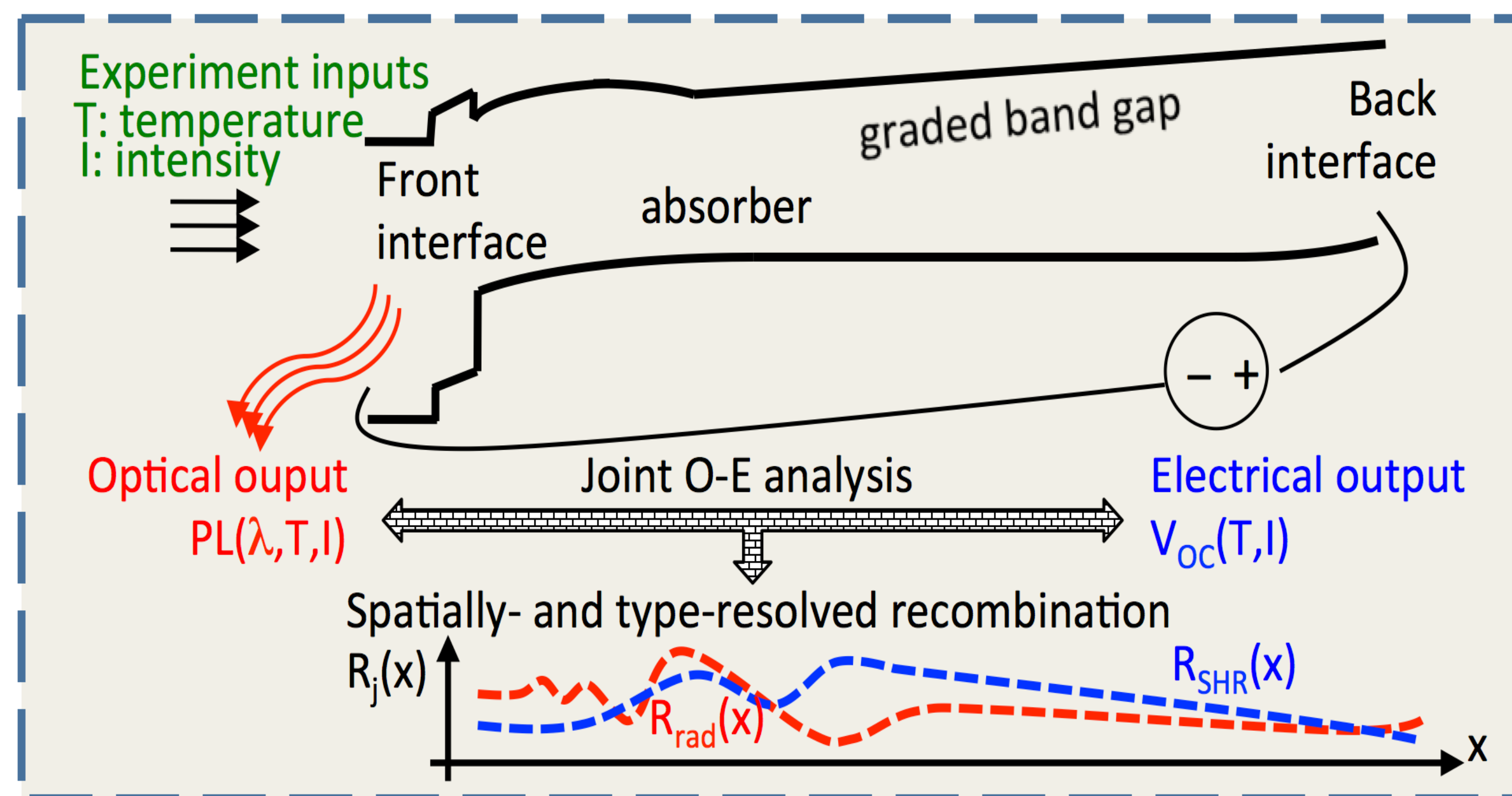
PHOTOVOLTAICS

Overview

Technology Addressed: Topic area 3: Pushing the limits of established PV technologies

Motivation

Voc engineering is only as good as the metrology employed whereas a metrology is only as good as the metrics it uses. State-of-the-art metrologies use 3rd-level metrics, e.g., saturation current density J_0 and carrier lifetime τ . These single lumped parameters cannot describe the **spatially distributed and non-uniform** recombination in TFPV, which calls for the 4th-level metric of spatially- and type-resolved recombination $R_j(x)$.



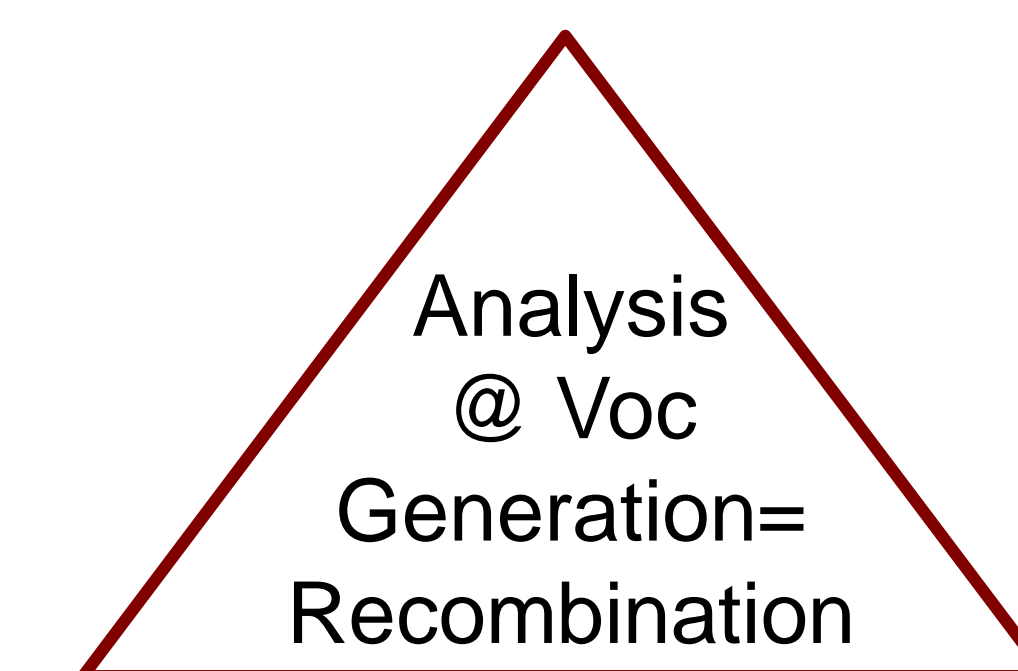
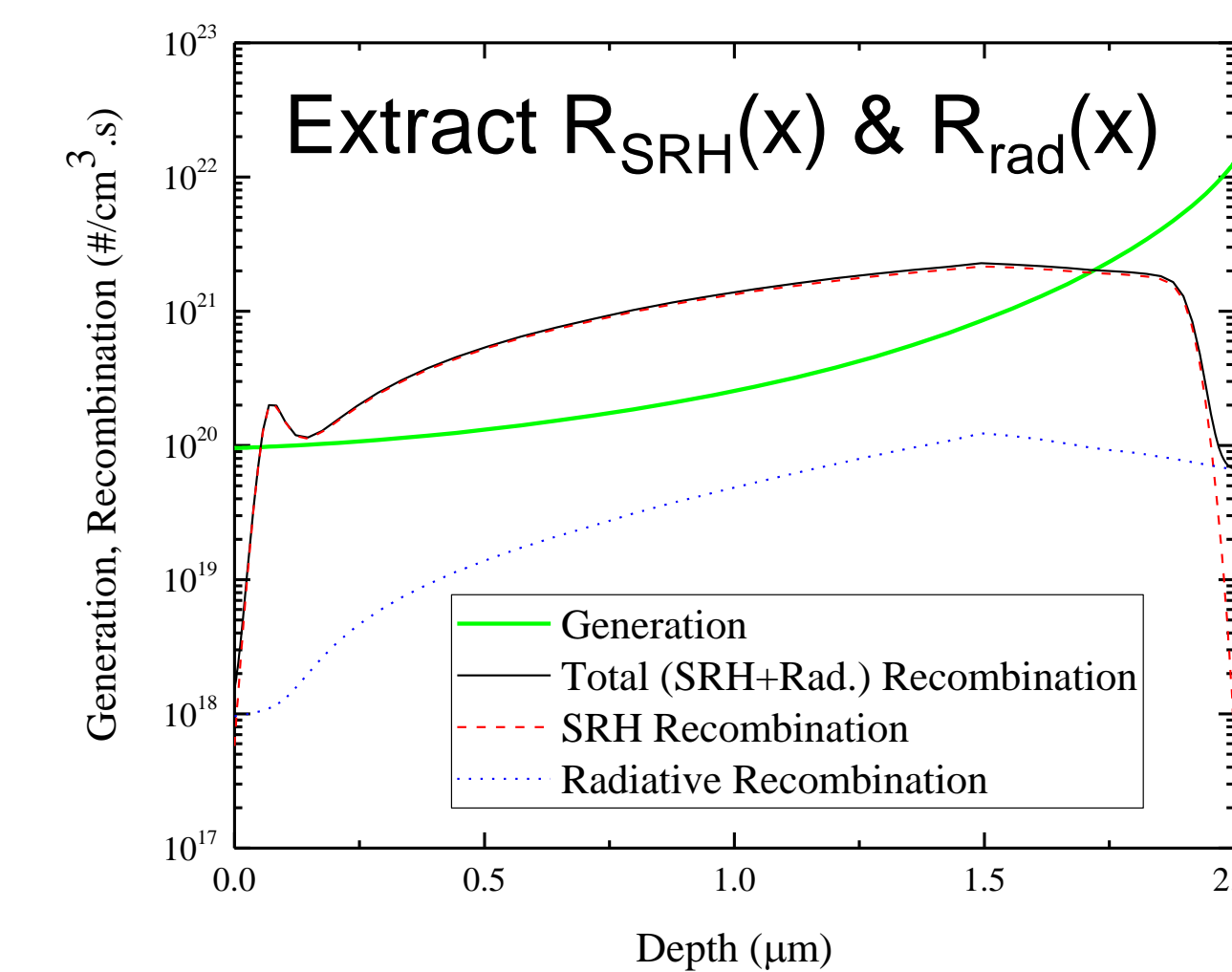
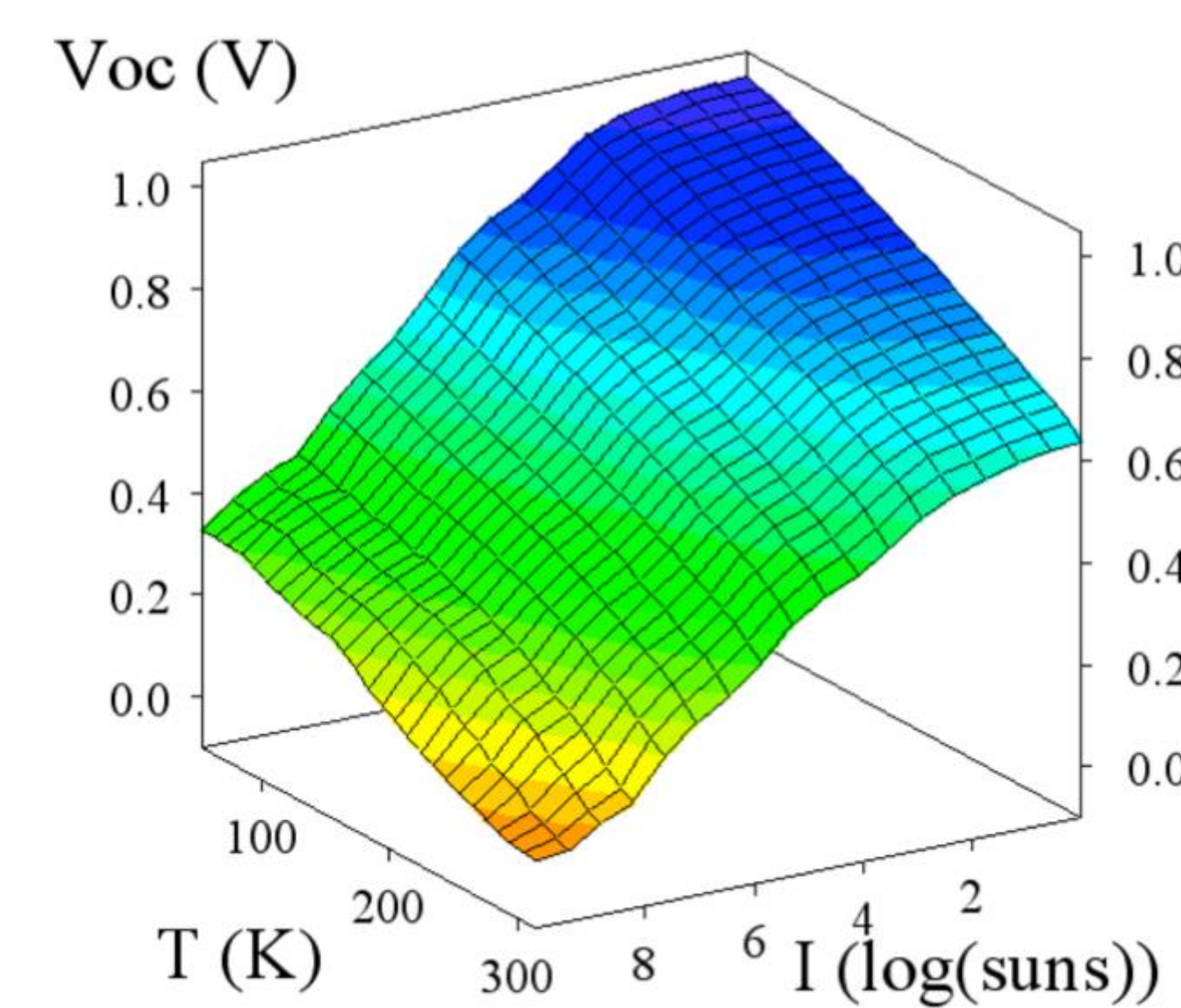
Impact

- Advance the state-of-the-art of recombination metrology
- Enable metrology-guided V_{OC} engineering for TFPV
- Catalyze the advancement of Voc and materially improve module performance, manufacturability, and reliability towards the \$0.06/kWh SunShot goal.

Technical Approaches

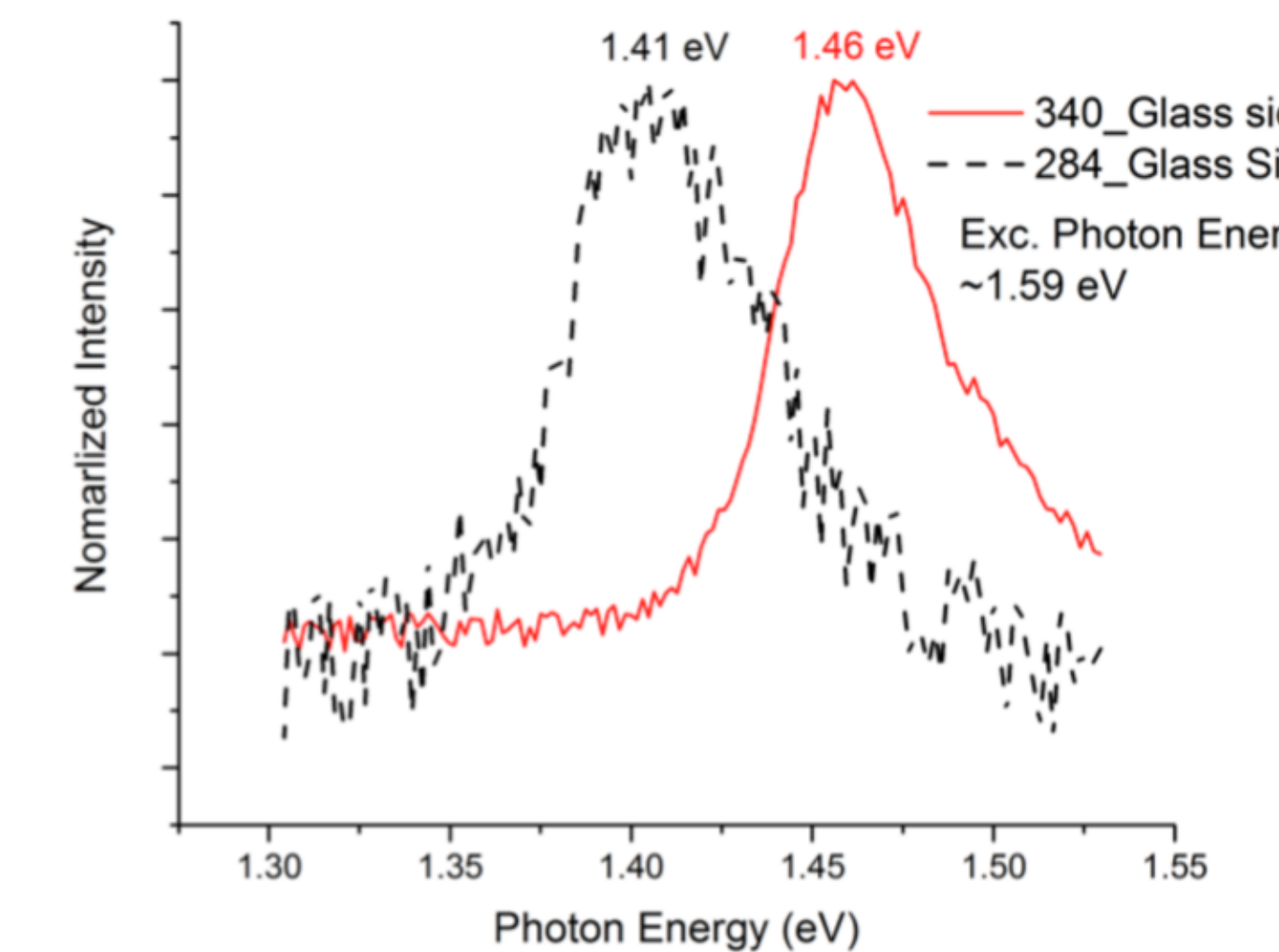
Electrical Char. $V_{OC}(T, I)$:
 $R_{SRH}(x) + R_{rad}(x)$

Predecessors:
 $V_{OC}(T)$, Suns-Voc, $V_{OC}(T, I)$



Optical Char. $PL(\lambda, T, I)$:
 $R_{rad}(x)$ only

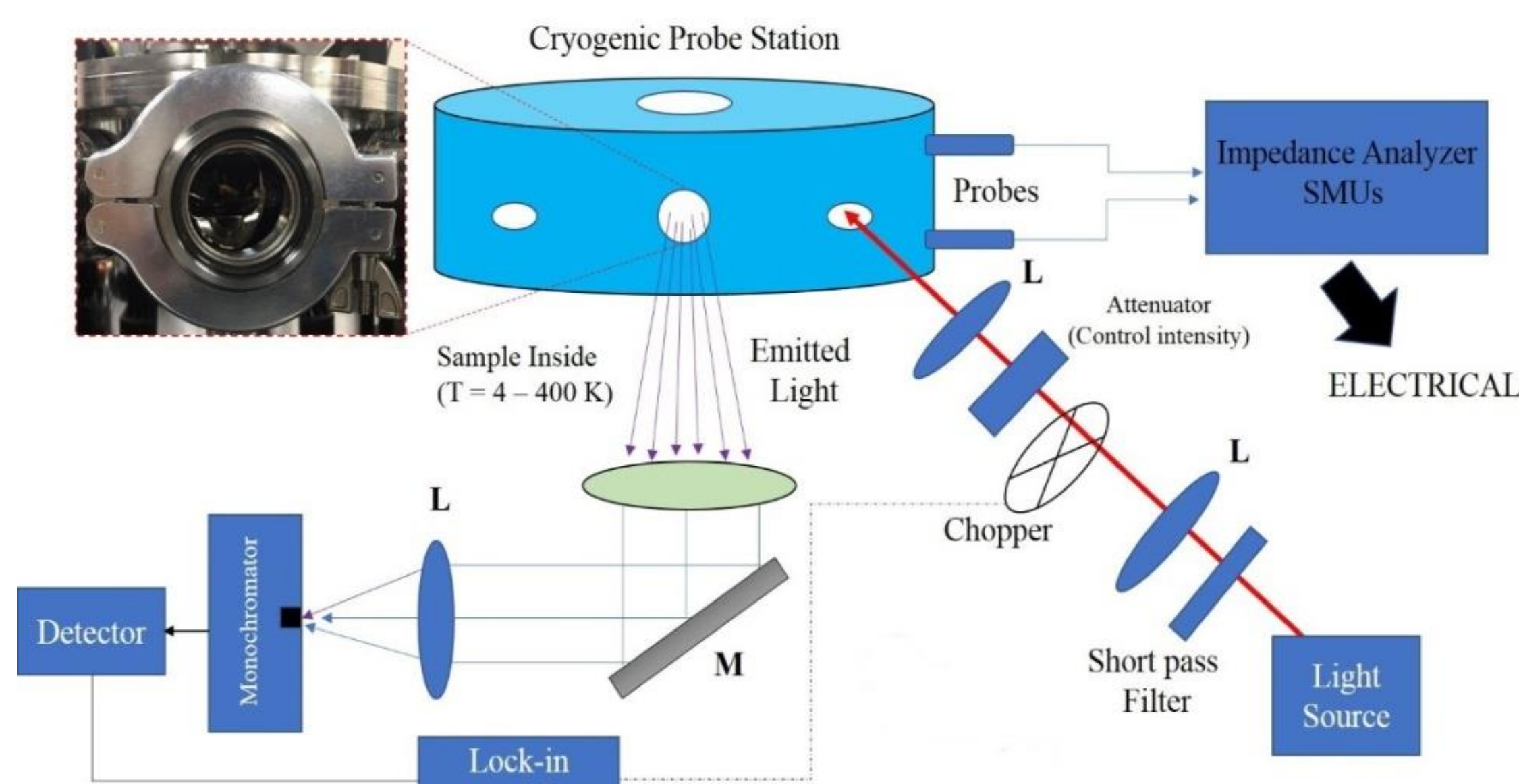
Predecessors:
 Conventional $PL(T, I)$
 Generalized Planck's equation



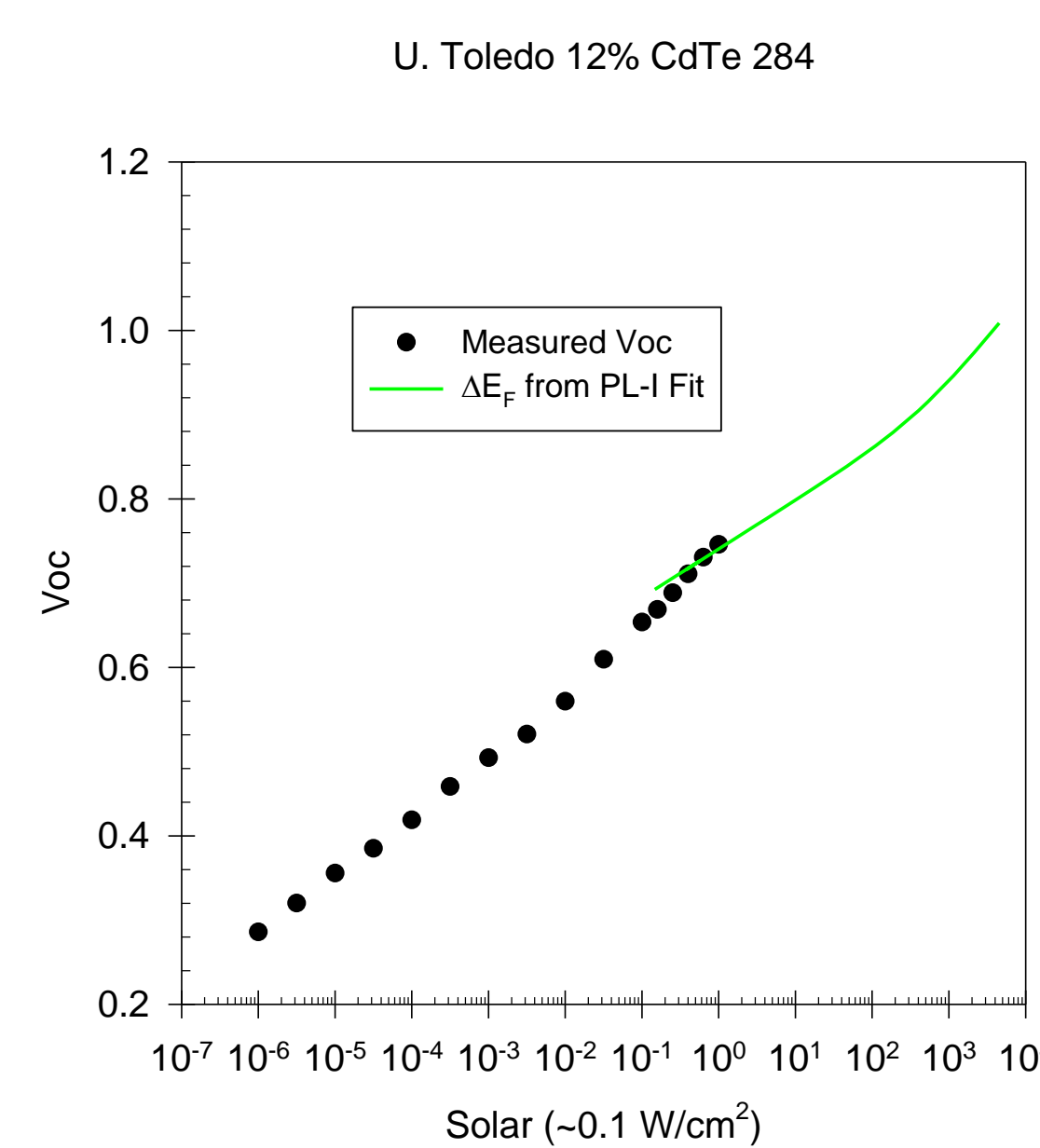
Innovative Aspect

We develop a transformative metrology based on the 4th-level metric – the spatially and type-resolved recombination rate $R_j(x)$. This metrology is built upon joint electrical-optical analysis that simultaneously solves the SRH and radiative recombination.

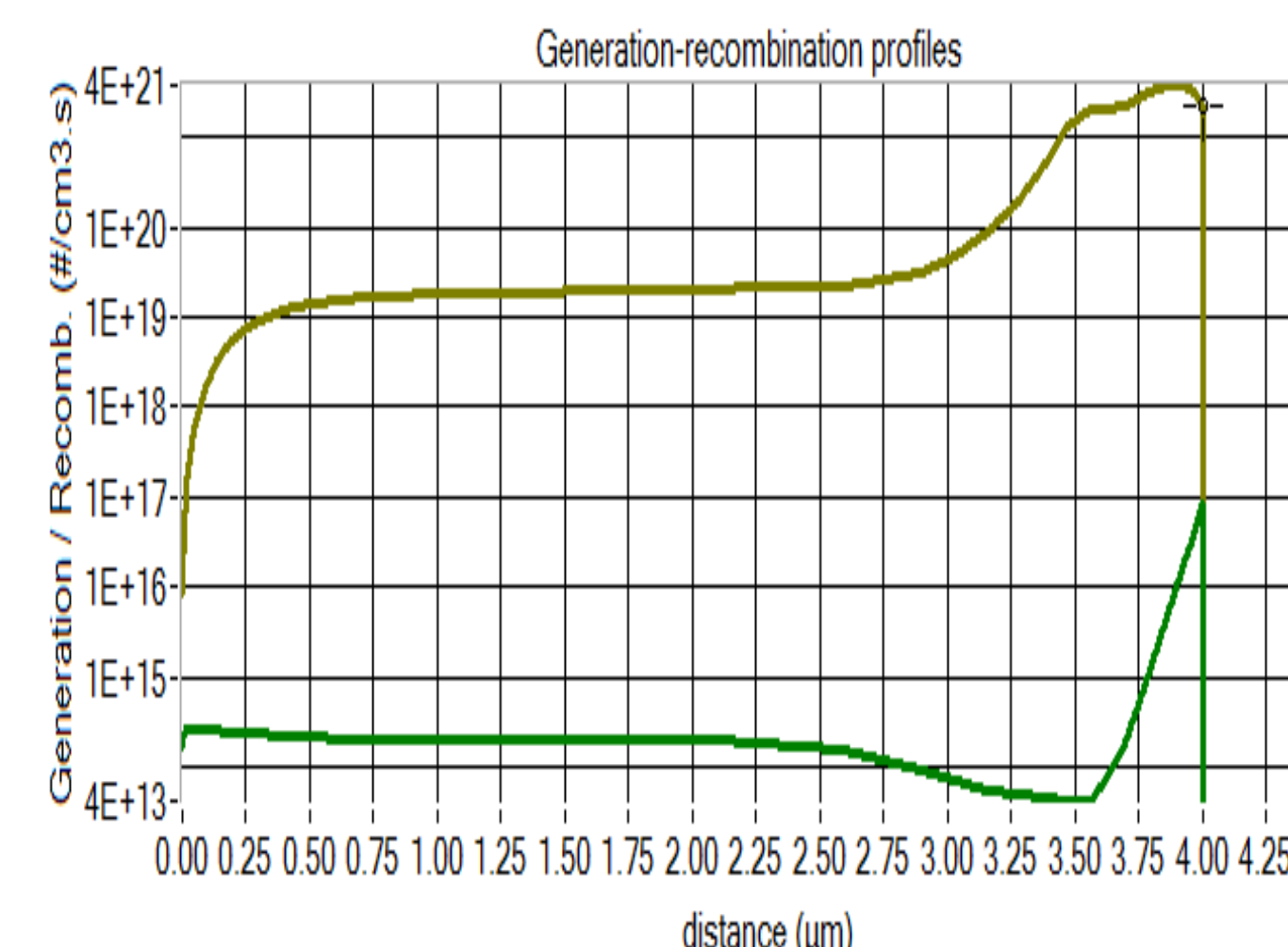
Progress



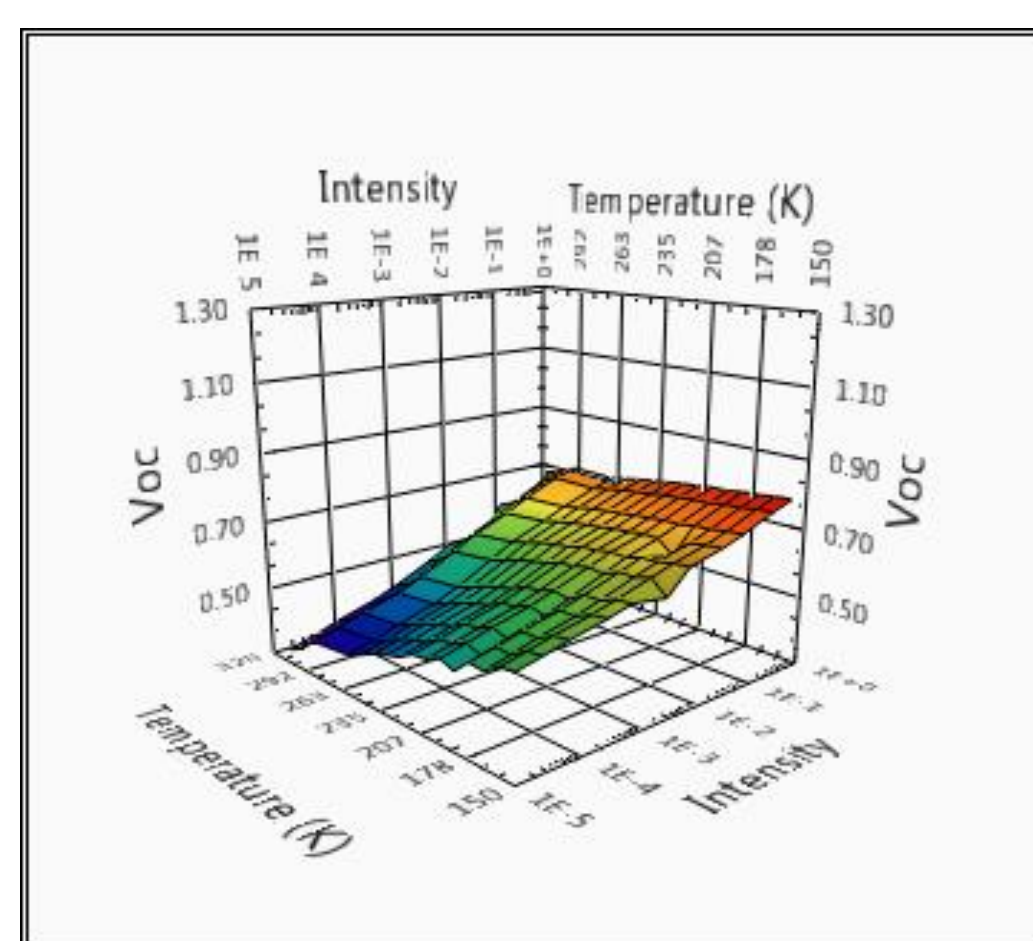
Electrical and optical measurement setup at Texas State University



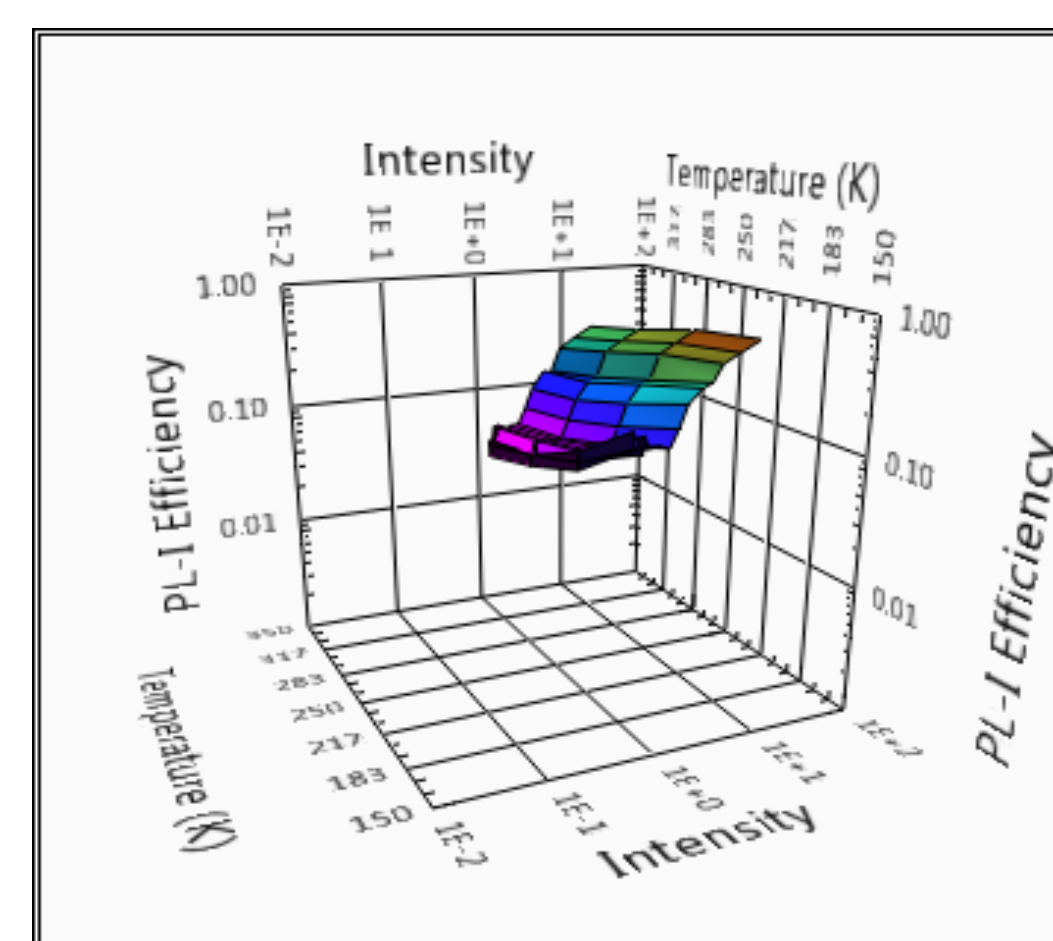
Extraction of Fermi level splitting from PLI



$R_{SRH}(x)$ and $R_{rad}(x)$ extracted for the idea scenario

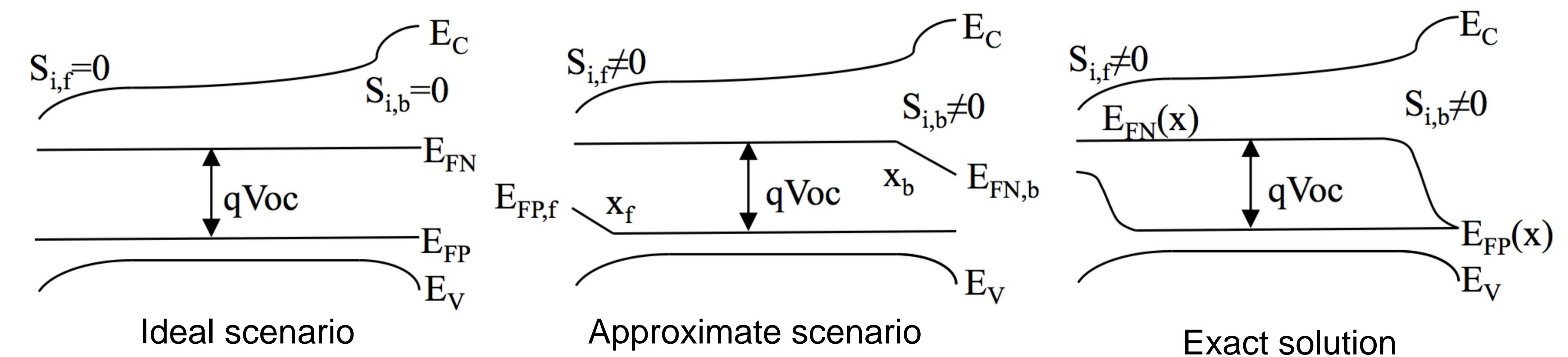


$V_{OC}(T, I)$ data from a CdTe device



$PL(T, I)$ data from a CdTe device

Future work



Year 1 objectives

Extract $R_{rad}(x)$ and $R_{SRH}(x)$ profiles with:

- spatial resolution $dx < 50$ nm;
- dynamic range $R_{SRH,max}/R_{SRH,min} > 10$ for the approximate scenario in thin-film PV devices;
- calibration with J_0 method to within a factor of 3 in Si devices.

Future Work

- Proposed work is to develop the $R_j(x)$ metrology for TFPV
- 1) Develop a $R_j(x)$ metrology for the approximate scenario for TFPV and validate with Si
- 2) Develop a $R_j(x)$ metrology for exact-solution scenario and use it to guide Voc improvement for industrial partners
- 3) Develop a rapid $R_j(x)$ metrology for module manufacturing